

EAST Search History

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|---|---|------------------|---------|------------------|
| L1 | 1 | (inspect\$3 and substrat\$3 and defect\$1 and light\$3 and beam\$1 and scatter\$3 and compar\$3 and intensit\$3 and maximum and value\$1).clm. | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2006/06/01 10:14 |
| L2 | 0 | 356/237.100.ccls. | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2006/06/01 10:14 |
| L3 | 2407 | 356/237.1.ccls. | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2006/06/01 10:14 |
| L4 | 0 | (inspect\$3 and substrat\$3 and defect\$1 and light\$3 and beam\$1 and scatter\$3 and compar\$3 and intensit\$3 and maximum and value\$1).clm. and l3 | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2006/06/01 10:14 |



Welcome United States Patent and Trademark Office

[Search Results](#)[BROWSE](#)[SEARCH](#)[IEEE XPLORE GUIDE](#)

Results for "((inspect and substrate and intensities and scatter and light and compare and maximum and value and ..."

e-mail

Your search matched 0 documents.

A maximum of 100 results are displayed, 25 to a page, sorted by **Relevance** in **Descending** order.

» Search Options

[View Session History](#)[New Search](#)

Modify Search

☐ Check to search only within this results setDisplay Format: ☒ Citation ☐ Citation & Abstract

» Key

IEEE JNL IEEE Journal or Magazine

IEE JNL IEE Journal or Magazine

IEEE CNF IEEE Conference Proceeding

IEE CNF IEE Conference Proceeding

IEEE STD IEEE Standard

No results were found.

Please edit your search criteria and try again. Refer to the Help pages if you need assistance with your search.

Indexed by
[Help](#) [Contact Us](#) [Privacy &](#)

© Copyright 2006 IEEE –